



PATENT

Customer No. 22,852

Attorney Docket No. 07553.0030 (formerly 07363.0010)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Reissue Application of: )

U.S. Patent No.: 5,792,261 )

Inventor: Kiichi HAMA et al. )

Issued: August 11, 1998 )

Serial No.: 09/478,370 )

Filed: February 16, 2000 )

For: PLASMA PROCESS  
APPARATUS )

# 23E  
10/23/02  
MW

Group Art Unit: 1763

Examiner: L. Alejandro Mulero

Commissioner for Patents  
Washington, DC 20231

Sir:

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TC 1700 MAIL ROOM

AMENDMENT

In response to the Office Action dated August 7, 2002, please amend the application as follows:

IN THE CLAIMS:

Please amend the claims as follows:

165. (Amended) An apparatus for processing a process region of a substrate,

using a plasma, comprising:

a container substantially formed of a conductive material;

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